

NOV 03 2005

CHEMICAL MECHANICAL POLISHING PROCESS

Appl. No. : 10/711,392 Confirmation No. 5391
Applicant : Chia-Lin Hsu,
Teng-Chun Tsai
Filed : September 16, 2004
TC/A.U. : 3723
Examiner : Jacob K. Ackun Jr.
Docket No. : NAUP0633USA0
Customer No. : 27765

Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

5 Subject: Request for Continued Examination (RCE) in response to the advisory
action mailed 10/14/2005

INTRODUCTORY COMMENTS

10 In response to the Office action identified above, a request for continued
examination (RCE) is made and the above-identified application is to be amended as
indicated in the following sections. No new matter has been introduced by these
amendments. A continued examination and consideration of all amendments are
politely requested.

15 Amendments to the Claims are reflected in the listing of claims beginning on page 2 of
this paper.

Remarks begin on page 4 of this paper.